

VIS-86-118CB



IP-1765
#3

August 14, 2001

To: Commissioner of Patents and Trademarks
Washington, D.C. 20231

Fr: George O. Saile, Reg. No. 19,572
20 McIntosh Drive
Poughkeepsie, N.Y. 12603

Subject:

Serial No. 09/891,861 06/25/01

Randy Chang

COAXIAL DRESSING FOR CHEMICAL
MECHANICAL POLISHING

Grp. Art Unit: 1765

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INFORMATION DISCLOSURE STATEMENT

Enclosed is Form PTO-1449, Information Disclosure Citation
In An Application.

The following Patents and/or Publications are submitted to
comply with the duty of disclosure under CFR 1.97-1.99 and
37 CFR 1.56. Copies of each document is included herewith.

U.S. Patent 5,681,212 to Hayakawa et al., "Polishing
Device and Correcting Method Therefor", discloses a polish
head.

U.S. Patent 5,624,299 to Shendon, "Chemical Mechanical
Polishing Apparatus with Improved Carrier and Method of Use",
discloses a carrier head with a polish pad and retaining ring.

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U.S. Patent 5,664,987 to Renteln, "Methods and Apparatus for Control of Polishing Pad Conditioning for Wafer Planarization", discloses a method and apparatus to condition a polish pad using a conditioning track on the polish pad.

U.S. Patent 5,616,063 to Okumura et al., "Polishing Apparatus", discloses a polishing apparatus with multiple heads.

U.S. Patent 5,605,499 to Sugiyama et al., "Flattening Method and Flattening Apparatus of a Semiconductor Device", discloses a standard chemical mechanical polishing head.

Sincerely,

A handwritten signature in cursive script that reads "George O. Saile". The signature is written in dark ink and is positioned above the printed name and registration number.

George O. Saile,
Reg. No. 19572

Form PTO-1449

INFORMATION DISCLOSURE CITATION
IN AN APPLICATION

(Use several sheets if necessary)

Document Number (Optional)

VIS-86-118CB

Application Number

09/891,861

Applicant

Randy Chang

Filing Date

06/25/01

Group Art Unit

1765

U. S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	TITLE	CLASS	SUBCLASS	ALOW DATE & APPROPRIATE
	5681212	10/28/97	Hayakawa et al.	451	288	4/5/96
	5664987	9/9/97	Renteln	451	21	9/4/96
	5624299	4/29/97	Shendon	451	28	5/1/95
	5616063	4/1/97	Okumura et al.	451	1	9/20/94
	5605499	2/25/97	Sugiyama et al.	451	443	4/13/95

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Portion of Pages, Etc.)

EXAMINER

DATE CONSIDERED

AMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.